

EAST - [Untitled1:1]

File View Edit Tools Window Help

Drifts
Pending
Active
L1: (134) "4475582" or "8497272" or "4180119" or "4450885" or "4133388" or "
L2: (591) (single adj crystal) same select33 same read
L3: (0) 2 and (select33 near10 (support33 or strength35))
L4: (18) 2 and (select33 near10 (support33 or strength35))
L5: (358) 2 not 1 not 4
Failed
2 and (select33 near10 (support33 or strength35))
Saved
Favorites
Tagged (8)
UDC
Queue
Trash

AS FIVE UGAT ENG APP DETENT 04_08
Work order: DR
N. D. 0000
17 (358,21 41 71 1000 1000)

not a note

U	Document ID	Issue Date	Pages	TIME	Current OR	Current OR Ref	Retrieval Class	Inventor	S	C	P	A	B	in
1	US 20050072432 A1	20050407	8	Single crystals of lead magnesium niobate-lead titanate	117/8			Eisler, Elgin E.						US
2	US 20050085049 A1	20050324	8	Chemical composition for use with group IIA metal fluorides	510/170	510/175		Burdo, Ronald A. et al.						US
3	US 20050084206 A1	20050324	16	GALLIUM-NITRIDE DEPOSITION SUBSTRATE, METHOD OF	428/448	117/85; 428/698		Akita, Katsushi et al.						US
4	US 20050045300 A1	20050303	6	Apparatus and method for producing single crystal metallic objects	184/122.2	184/338.1		Huang, Shyh-Chin et al.						US
5	US 20050025613 A1	20050203	12	Integral turbine composed of a cast single crystal blade ring diffusion	415/1			Strangman, Thomas E.						US
6	US 20050022721 A1	20050203	11	Ascentric, rhombohedral lanthanide borate crystals, method for making,	117/11			Koels, Joseph W.						US
7	US 20050022720 A1	20050203	12	Ascentric orthorhombic lanthanide borate crystals, method for making,	117/2	423/263		Koels, Joseph W. et al.						US
8	US 20040288137 A1	20041230	8	Method of fabricating a wafer with strained channel layers for increased	438/458	438/149; 438/478;		Huang, Chien-Chao et al.						US
9	US 20040255845 A1	20041223	10	System and method for forming single-crystal domains using crystal	117/92			Voutsas, Apostolos T. et al.						US
10	US 20040251471 A1	20041218	18	Light emitting element structure using nitride bulk single crystal layer	257/103	257/98		Dadineki, Robert et al.						US
11	US 20040251333 A1	20041216	13	Method and apparatus for improving silicon processing efficiency	241/24.1			Arvidson, Arvid Neil et al.						US

Ready

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